

Attorney's Docket No.: 07977-270001 / US4820

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Yonezawa, et al. Art Unit : 1763  
Serial No.: 09/820,520 Examiner : Luz L. Alejandro  
Filed : March 28, 2001 Confirmation No. : 5433  
Title : PLASMA CVD DEVICE AND DISCHARGE ELECTRODE

Commissioner for Patents  
Washington, D.C. 20231

AMENDMENT

Sir:

In response to the Official Action dated August 7, 2002,  
Paper No. 5, in the above-referenced application, please amend  
the above-identified application as follows.

In the Claims:

Please amend claim 1 as follows:

1. (Amended) A plasma CVD apparatus comprising:  
a vacuum chamber;  
an introducing means for introducing a gas into the vacuum  
chamber;  
an exhaust means for exhausting the gas from the vacuum  
chamber to an outside;

## CERTIFICATE OF TRANSMISSION BY FACSIMILE

I hereby certify that this correspondence is being transmitted by  
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November 7, 2002  
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